

<b>Model No:</b>	<b>Description:</b>
XeLM-L	<p><b>Xenon Vacuum Ultraviolet (VUV) Line Source</b></p> <p>This Xenon filled RF powered lamp system is a reliable and maintenance free high intensity source of deep VUV emissions at <b>147.0 NM</b>. This source mounts to a 2.75 inch CF flange for convenient connection to a HV system. VUV fluxes greater than 5 milliwatts are delivered through the output window for use in vacuum applications such as photoluminescence, photoionization, photolithography and mass spectroscopy.</p>

Electrical /Optical Specifications/General:				
Specification	Minimum	Typical	Maximum	units
Gas Fill		Xenon		na
Peak wavelengths	-	147.0	-	NM
Full Spectral Range	-	129 to 7,000	-	NM
VUV Intensity	$5 \times 10^{15}$	$9 \times 10^{15}$	$1.3 \times 10^{16}$	Photons/sec/steradian
Full angle output cone	30	45	65	Degrees
Window Material		MgF <sub>2</sub> / Sapphire		na
Clear Aperture of window		0.9		CM.
Pulse	Modulation to 1 kHz available as option			
Certification	Calibration of Irradiance in Vacuum			
Plasma diameter	0.8	0.9	1.0	CM.
Plasma length	2	2.5	3.0	CM.
Input Power	20	25	30	Watts
Input voltage	95	115	260	VAC
Input Line Frequency	50	60	65	Hz
Mounting flange	2.75 inch Conflat is standard, lamp can be sealed to 10 <sup>-7</sup> torr system			
Cooling	Air cooling			
Intensity monitor	Intensity monitor available as an option			
Thermal control	na			
System	Complete system includes AC to DC power supply, RF power supply, EMI shielded enclosure, Vacuum flange, case, manual and calibration			

## Xe VUV Line Spectrum

